

1764



PATENT
5480-00201/OP99140_US-CPA

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Dong-soo Kim

Serial No 09/287,602

Filed: April 7, 1999

For: **GAS SCRUBBER FOR TREATING
THE GAS GENERATED DURING THE
SEMICONDUCTOR
MANUFACTURING PROCESS**

Group Art Unit: 1764

Examiner: Tran, H.

Atty. Dkt. No. 5480-00201

#120
8/30/02
MW

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: **Box Non-Fee Amendment**, Assistant Commissioner for Patents, Washington, D.C. 20231, on the date indicated below:

8/13/02

Date

Kevin L. Daffer

AMENDMENT; RESPONSE TO OFFICE ACTION MAILED MAY 17, 2002

Box: Non-Fee Amendment
Assistant Commissioner for Patents
Washington, D.C. 20231

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Dear Sir/Madam:

This paper is submitted in response to the Office Action mailed May 17, 2002 to further highlight reasons why the application is in condition for allowance.

Please amend the case as follows.

IN THE SPECIFICATION

Please replace pg. 6, line 23 - pg. 7, line 2, of the amended Specification (Attachment A of the Response to the Office Action mailed October 4, 2000) with the amended paragraph below. A "marked-up" version of each amendment is included in **Attachment A**.